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6-22-00
R. GradenPATENT
Atty. Docket No. MIT-106
(5473/112)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Michael Mermelstein ✓
 SERIAL NO.: 09/274,601 ✓ GROUP NO.: 2878 ✓
 FILING DATE: March 23, 1999 ✓ EXAMINER: David Spector
 TITLE: OPTICAL SYNTHETIC APERTURE ARRAY ✓

Assistant Commissioner for Patents
 Washington, D.C. 20231

PRELIMINARY AMENDMENT

Applicant hereby submits this preliminary amendment for entry in the above-referenced patent application.

In the Claims

06/22/2000 RGRADEN 00000001 200531 09274601
 Please amend Claims 1-4, 7, 9, 11-13, and 19-21:

01 FC:103 1. ^{18-AO-CH} ~~An~~ ^(AMENDED) Interferometric microlithography [synthetic aperture] system for producing a spatially non-periodic pattern [in a region of overlap] comprising:

a source of coherent electromagnetic radiation producing a plurality of coherent electromagnetic beams;

a plurality of beam controllers, each of said beam controllers positioned to receive a respective one of said plurality of said coherent electromagnetic beams and direct said respective coherent electromagnetic beam into a [said] region of overlap defined by an intersection of all of said plurality coherent electromagnetic beams; and

Adjustment date: 05/23/2000 RGRADEN
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